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SERIAL NUMBER 08/958,460	FILING DATE 10/28/1997 RULE -	CLASS 216	GROUP ART UNIT 1711	ATTORNEY DOCKET NO. UMC-96-279
APPLICANTS CHIH-CHEN LIU, TAIPEI, TAIWAN; TA-SHAN TSENG, TAIPEI, TAIWAN; WEN-BIN SHIEH, HSIN-CHU CITY, TAIWAN; JUAN-YUAN WU, HSIN-CHU CITY, TAIWAN; WATER LUR, TAIPEI, TAIWAN; SHIH-WEI SUN, TAIPEI, TAIWAN;				
** CONTINUING DATA ***** THIS APPLN CLAIMS BENEFIT OF 60/041,790 04/02/1997				
** FOREIGN APPLICATIONS *****				
Foreign Priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions met <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance Verified and Acknowledged <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance		STATE OR COUNTRY TAIWAN	SHEETS DRAWING 4	TOTAL CLAIMS 20
Examiner's Signature _____ Initials _____		INDEPENDENT CLAIMS 3		
ADDRESS 23995				
TITLE HIGH DENSITY PLASMA CHEMICAL VAPOR DEPOSITION PROCESS				
FILING FEE RECEIVED 790	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	